

# Jakub Zlámal

## List of Publications by Year in descending order

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27  
papers

378  
citations

1039880

9  
h-index

794469

19  
g-index

27  
all docs

27  
docs citations

27  
times ranked

443  
citing authors

#	ARTICLE	IF	CITATIONS
1	Co doped YbFeO <sub>3</sub> : exploring the electrical properties via tuning the doping level. <i>Ionics</i> , 2019, 25, 4013-4029.	1.2	36
2	Accurate interpolation of 3D fields in charged particle optics. <i>Ultramicroscopy</i> , 2018, 189, 95-101.	0.8	4
3	Design of the charged particle diverter for the ATHENA mission. , 2018, , .		3
4	Rapid heating of zirconia nanoparticle-powder compacts by infrared radiation heat transfer. <i>Journal of the European Ceramic Society</i> , 2017, 37, 1067-1072.	2.8	6
5	Role of conduction and convection heat transfer during rapid crack-free sintering of bulk ceramic with low thermal conductivity. <i>Journal of the European Ceramic Society</i> , 2016, 36, 2955-2959.	2.8	7
6	Influence of Saturation of Magnetic Lens Material on Fields of Deflectors and Parasitic Fields. <i>Microscopy and Microanalysis</i> , 2015, 21, 188-193.	0.2	6
7	On the Calculation of SEM and FIB Beam Profiles. <i>Microscopy and Microanalysis</i> , 2015, 21, 206-211.	0.2	4
8	Accurate Interpolation of 3D Fields Close to the Optical Axis. <i>Microscopy and Microanalysis</i> , 2015, 21, 242-245.	0.2	3
9	Experimental optimization of power-function-shaped drive pulse for stick-slip piezo actuators. <i>Precision Engineering</i> , 2015, 42, 187-194.	1.8	29
10	Calculation of the performance of magnetic lenses with limited machining precision. <i>Ultramicroscopy</i> , 2014, 137, 1-6.	0.8	6
11	Optimization of ion-atomic beam source for deposition of GaN ultrathin films. <i>Review of Scientific Instruments</i> , 2014, 85, 083302.	0.6	3
12	Guided Assembly of Gold Colloidal Nanoparticles on Silicon Substrates Prepatterned by Charged Particle Beams. <i>ACS Nano</i> , 2012, 6, 10098-10106.	7.3	34
13	Development of the program EOD for design in electron and ion microscopy. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2011, 645, 278-282.	0.7	21
14	Comparison of calculated, simulated and measured signal amplification in a variable pressure SEM. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 2011, 645, 79-83.	0.7	26
15	Microscopic Characterizations of Nanostructured Silicon Thin Films for Solar Cells. <i>Materials Research Society Symposia Proceedings</i> , 2011, 1321, 313.	0.1	0
16	An ultra-low energy (30â€“200ÂeV) ion-atomic beam source for ion-beam-assisted deposition in ultrahigh vacuum. <i>Review of Scientific Instruments</i> , 2011, 82, 083302.	0.6	9
17	Role of humidity in local anodic oxidation: A study of water condensation and electric field distribution. <i>Physical Review B</i> , 2009, 79, .	1.1	26
18	Mid-IR plasmonic antennas on silicon-rich oxinitride absorbing substrates: Nonlinear scaling of resonance wavelengths with antenna length. <i>Applied Physics Letters</i> , 2009, 95, .	1.5	5

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19	Numerical simulations of the thermionic electron gun for electron-beam welding and micromachining. <i>Vacuum</i> , 2009, 84, 357-362.	1.6	21
20	A new program for the design of electron microscopes. <i>Physics Procedia</i> , 2008, 1, 315-324.	1.2	51
21	The influence of humidity on the kinetics of local anodic oxidation. <i>Journal of Physics: Conference Series</i> , 2007, 61, 75-79.	0.3	7
22	In situ measurements of surface homogeneity of optical parameters of weakly absorbing thin films. <i>Surface and Interface Analysis</i> , 2002, 34, 664-667.	0.8	8
23	Comparison of FDM, FEM and BEM for electrostatic charged particle optics. <i>Nuclear Instruments and Methods in Physics Research, Section A: Accelerators, Spectrometers, Detectors and Associated Equipment</i> , 1999, 427, 357-362.	0.7	44
24	Deposition of magnetic thin films by IBAD. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , 1999, 148, 907-911.	0.6	8
25	Design of the entrance ion optics for SIMS and LEIS in situ monitoring of deposition processes. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , 1998, 136-138, 822-824.	0.6	1
26	Deposition of metal nitrides by IBAD. <i>Surface and Coatings Technology</i> , 1998, 108-109, 284-291.	2.2	6
27	Cleaning of metal surfaces by a broad beam ion source. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , 1997, 127-128, 865-868.	0.6	4